

BRUKER NANO ANALYTICS

# In-situ SEM nanoindentation combined with 3D EBSD

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Laurie Palasse, Ph.D.  
Senior Application Scientist, Bruker Nano Analytics

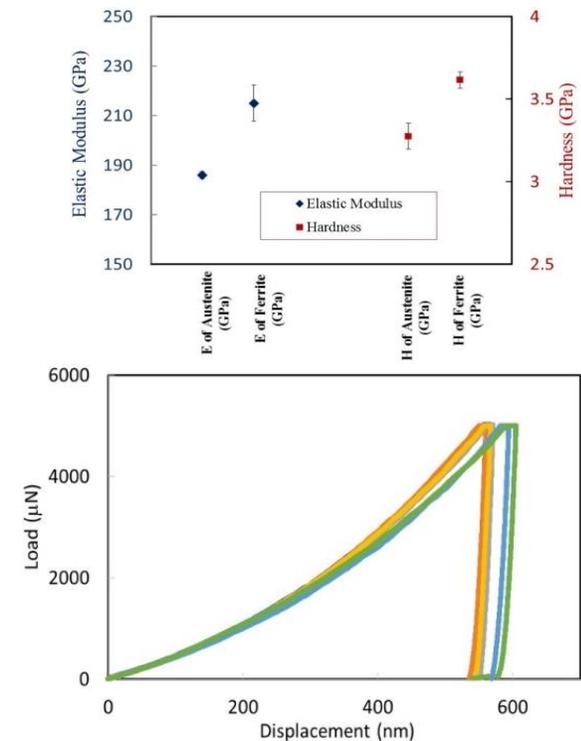
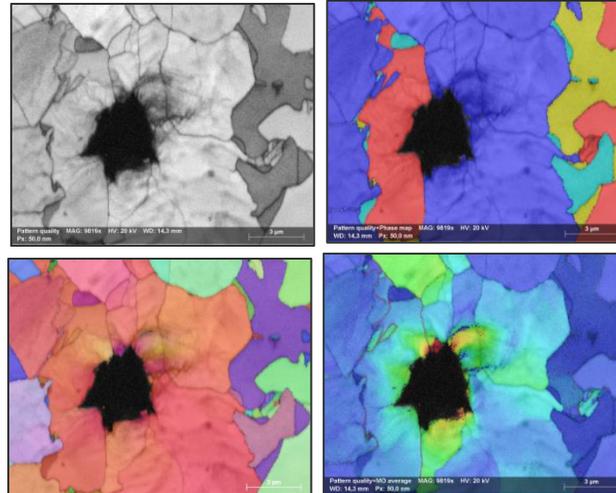
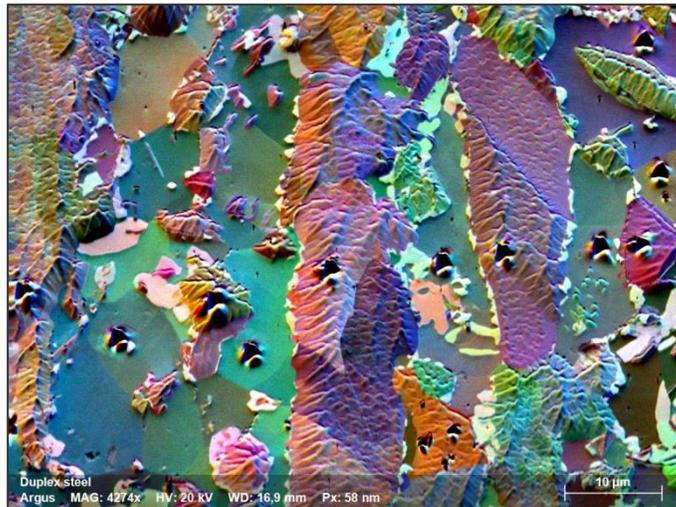
Jaroslav Lukes, Ph.D.  
Application Scientist, Bruker Nano Surface



EBSD/TKD

# In-situ SEM nanoindentation combined with EBSD

- Correlating mechanical properties with microstructural features
- Study of plastic deformation mechanisms, e.g. EBSD measurement of the deformed volume below the indent
- Investigation of residual stresses, e.g. with HR-EBSD measurement
- Tensile testing on thin lamella





# In-situ SEM nanoindentation combined with 3D EBSD

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- 01 In-situ nanoindentation with PI89
- 02 3D EBSD overview and data processing
- 03 Application example on austenitic steel
- 04 Summary

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# Nanomechanical testing setup PI89 SEM PicoIndenter

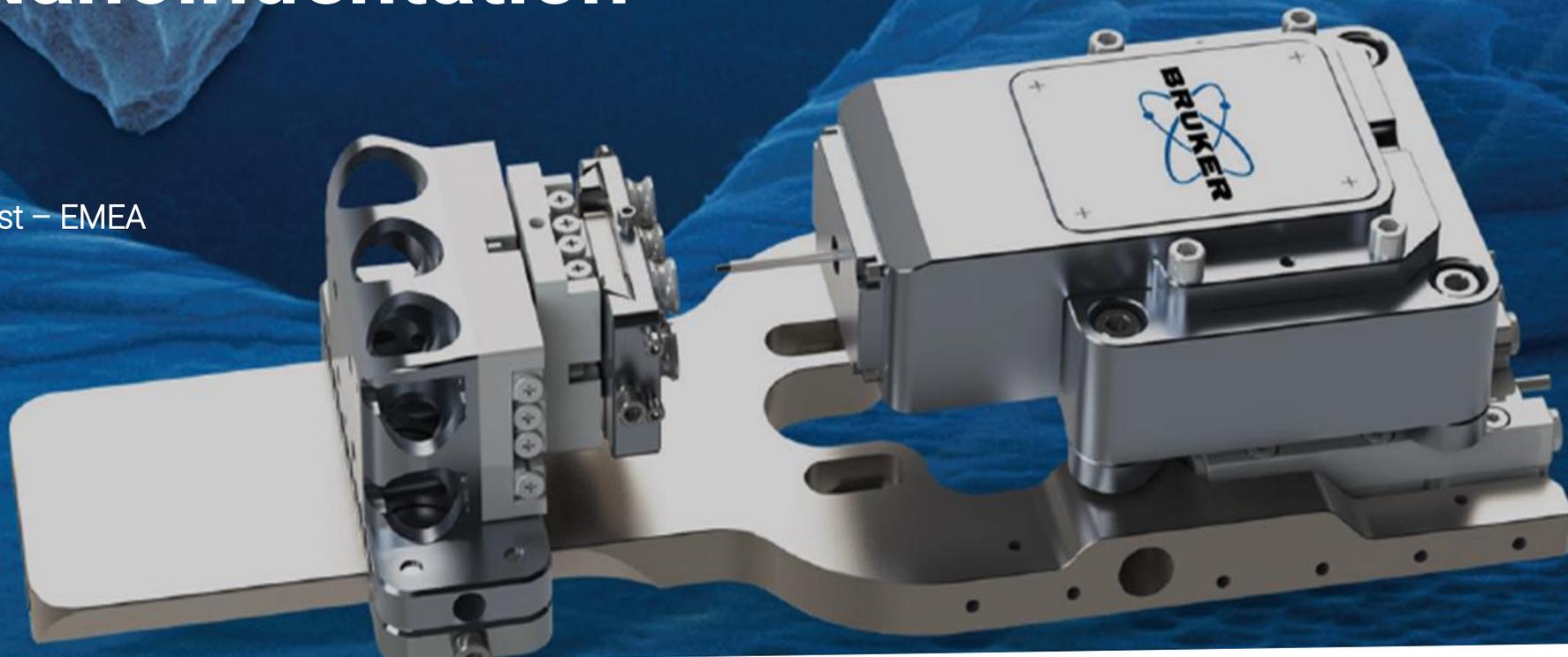
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BRUKER BNSM DIVISION

# In-situ SEM Nanoindentation

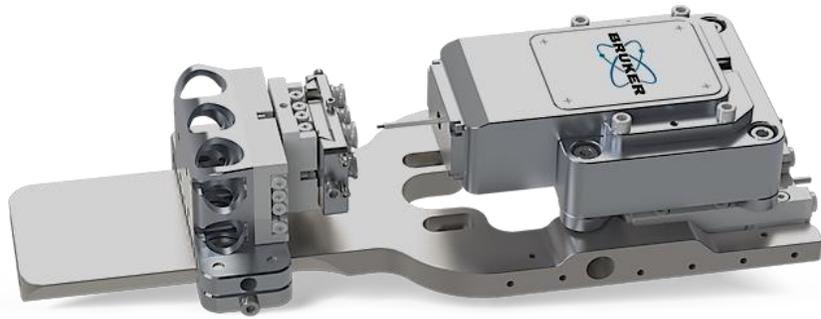
Jaroslav Lukeš, Ph.D.

Nanoindentation Applications Scientist – EMEA



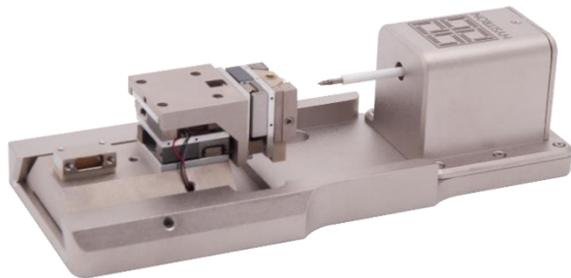
# Nanomechanical Instruments for Microscopes

**PI 89 SEM  
PicoIndenter®**



**PI 95 TEM  
PicoIndenter®**

**PI 85L SEM  
PicoIndenter®**



**BioSoft®**

**Intraspect360®**  
*for X-Ray Microscopes (XRM)  
Beamline/Synchrotron Sources*



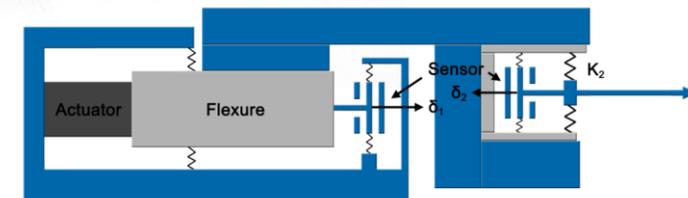
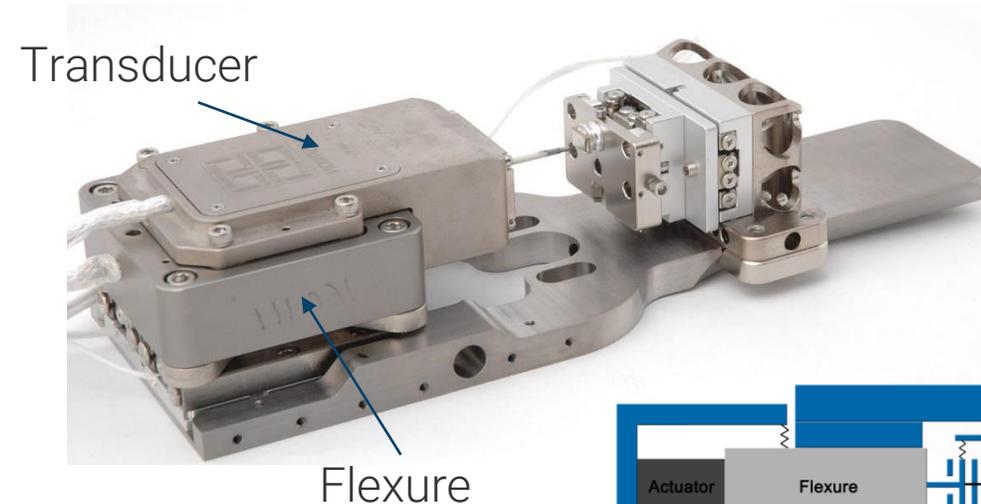
# Hysitron PI 89 SEM PicoIndenter

## B. xR Transducer with higher load – 3.5 N

- xR” Transducer- 10 mN, 500 mN and 3.5 N force and 150 μm displacement
- Max load 3.5 N and max displacement 150 μm
- Displacement actuation by intrinsically displacement-controlled piezo actuator
- In load control mode, electrostatic actuation is used

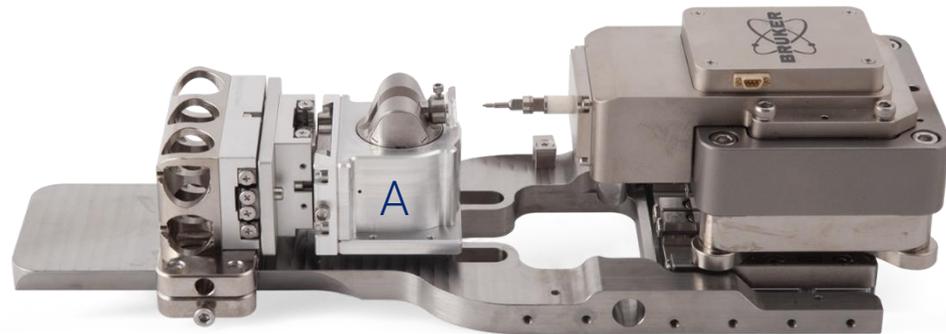


Replaceable “xR” Transducer:  
10 mN, 500mN and 3500 mN, 150 μm (flexure)



# Variable Sample Stage

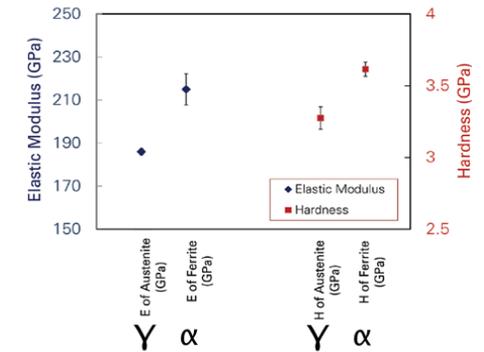
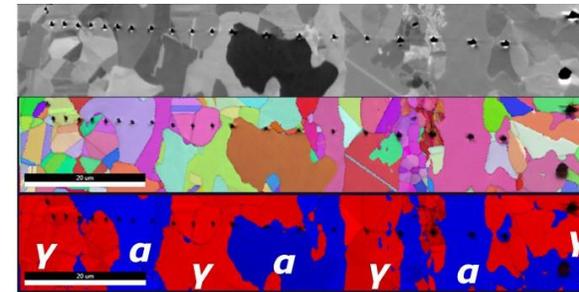
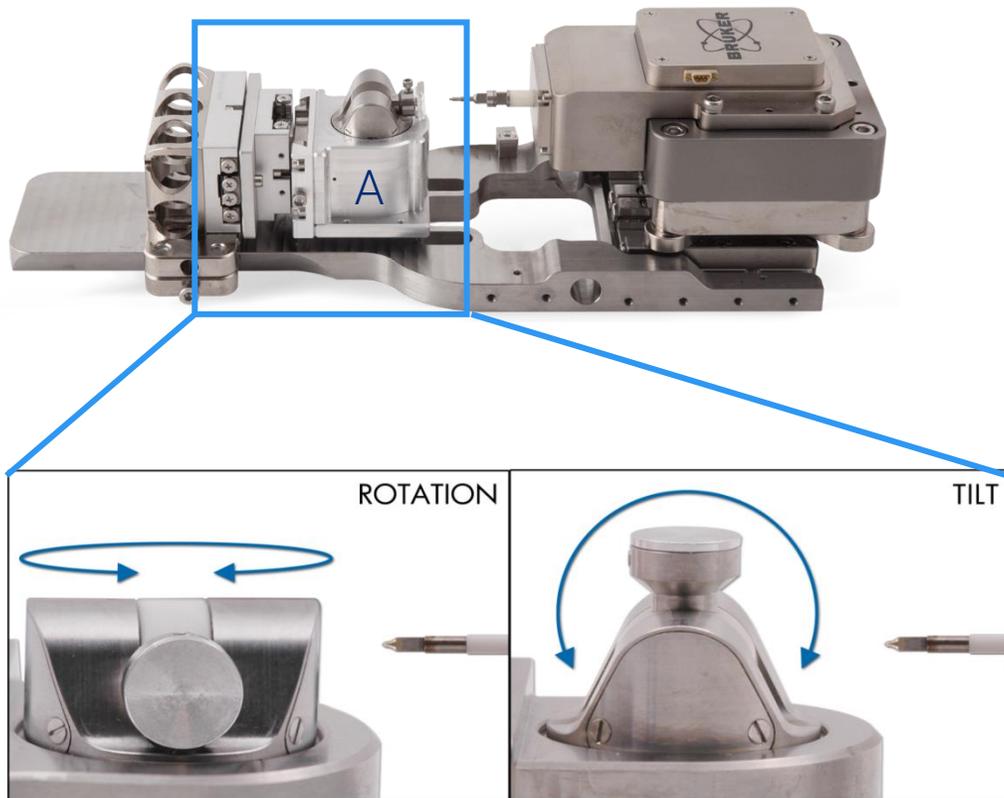
## Dual configuration rotation and tilt stage



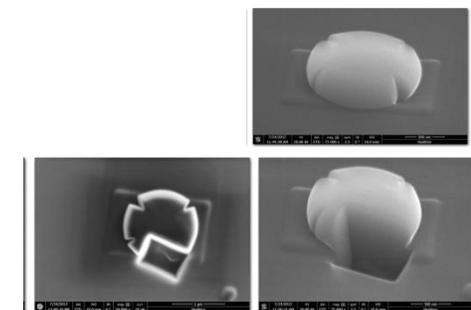
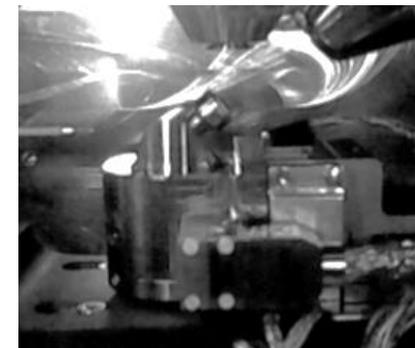
Patented in Japan and USA

# Rotation and Tilt Stage – Configuration A

- 5 Degrees of Freedom for Sample Positioning



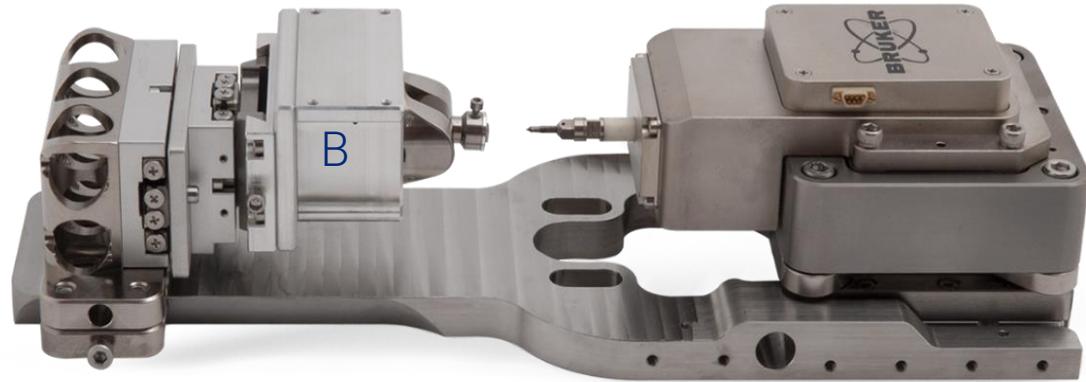
Indentation and EBSD mapping of phases of duplex steel (lower)



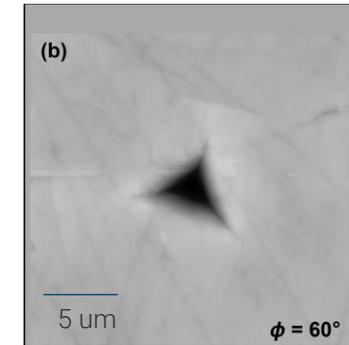
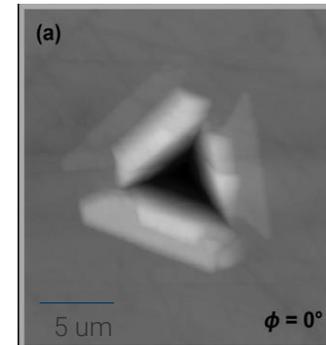
Particle compression and in-situ FIBing

Sample positioning towards **electron column for imaging**, FIB column for **milling**, and detectors such as EDS, BSE, EBSD, for **analytical data and imaging**.

# Rotation and Tilt Stage – Configuration B



- *5 Degrees of Freedom for Sample Positioning*



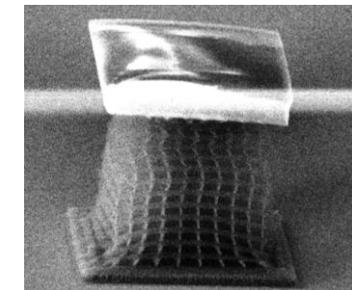
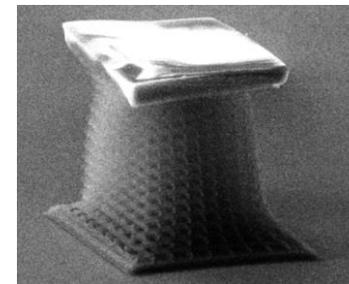
Example: Anisotropic indentation behavior in calcite  
(Courtesy; Prof. Shefford P. Baker, Cornell )



**Tilt-Rotation of a sample – Video**



**Spindle-Rotation of a sample – Video**



Spindle rotation of a pillar to observe other sides

5 um

Sample positioning towards **electron column for imaging**, detectors such as EDS, BSE, EBSD, for **analytical data and imaging, spindle-mode rotation of sample.**

# In-Situ Testing Techniques and Applications

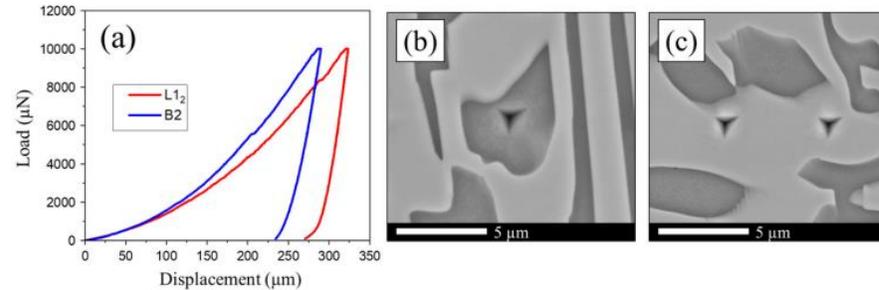
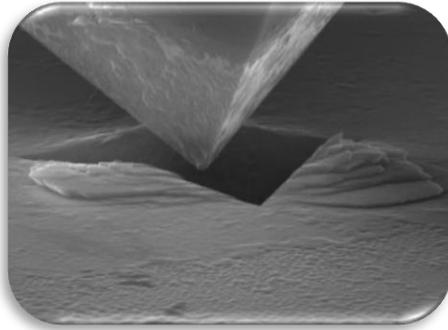
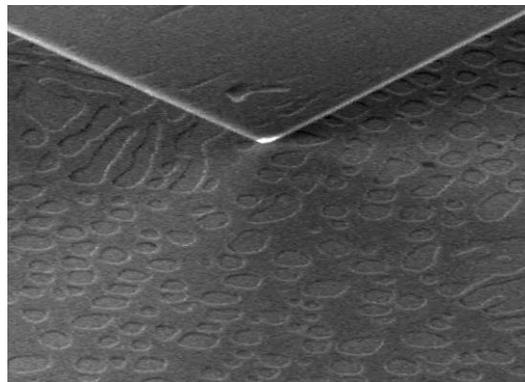


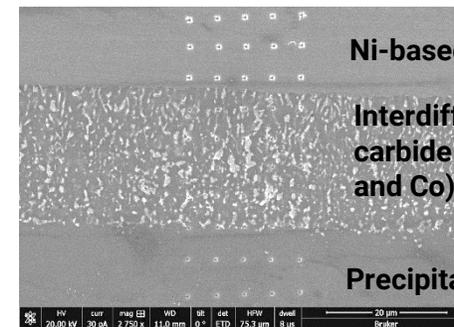
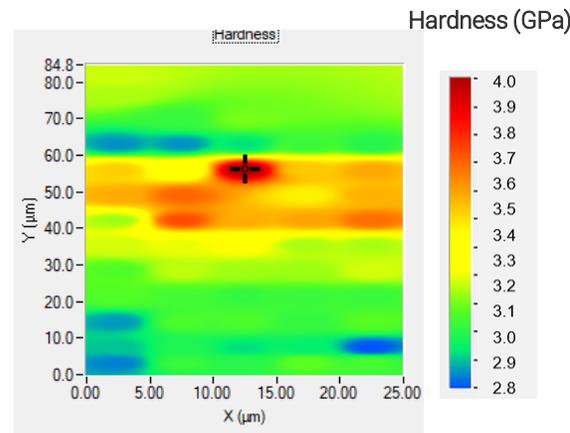
Fig. 6 a Load-displacement curves obtained from nano-indentation; SEM image of an indent: b on the B2 phase and c on the L12 phase

Eutectic high entropy alloy, Vahid Hasannaemi, Aditya V. Ayyagari, Saideep Muskeri, Riyadh Salloom and Sundeep Mukherjee, 2019, npj materials degradation, 3 (2019) 1886

## Integrated Accelerated Property Mapping (XPM) with PI 89



XPM- Video



Ni-based Superalloy substrate  
 Interdiffusion zone (contains carbide precipitates of W, Mo, Cr and Co)  
 Precipitate free NiAl

XPM with PI 89 : Available at High Temperature

XPM with PI 89 : RT Stage and EBSD

**Nanoindentation**  
**Accelerated Property Mapping (XPM)**

Compression

Direct Tension  
 PTP

Bending

DMA/Fatigue

Scanning Probe  
 Microscopy

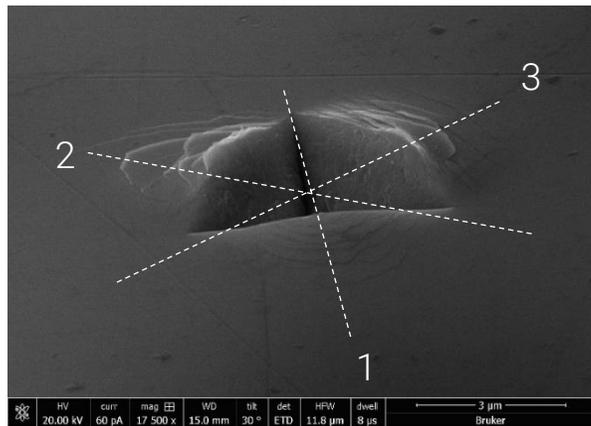
TKD

NanoTribology

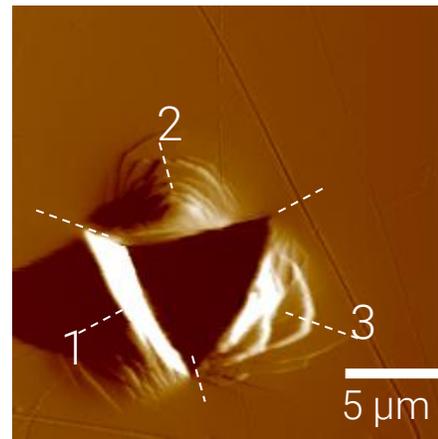
High Temperature

# In-Situ SEM Nanomechanics with SPM Imaging

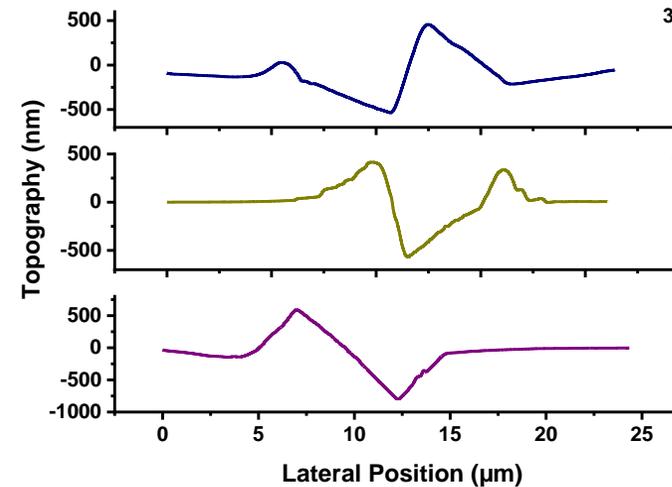
## SPM imaging and profile of an *in situ* SEM nanoindentation on bulk metallic glass



SEM image



SPM image



Profile across the indentation can quantify pile up volume and steps formed by slip bands.

- Topographical features can be viewed in high-resolution with secondary electron imaging in the SEM. However, quantitative topographical data is challenging.
- Accurate height information of sample features, surface roughness, pile-up or sink-in from nanoindentation.

Nanoindentation  
Accelerated Property  
Mapping  
(XPM)

Compression

Direct Tension  
PTP

Bending

DMA/Fatigue

**Scanning Probe  
Microscopy**

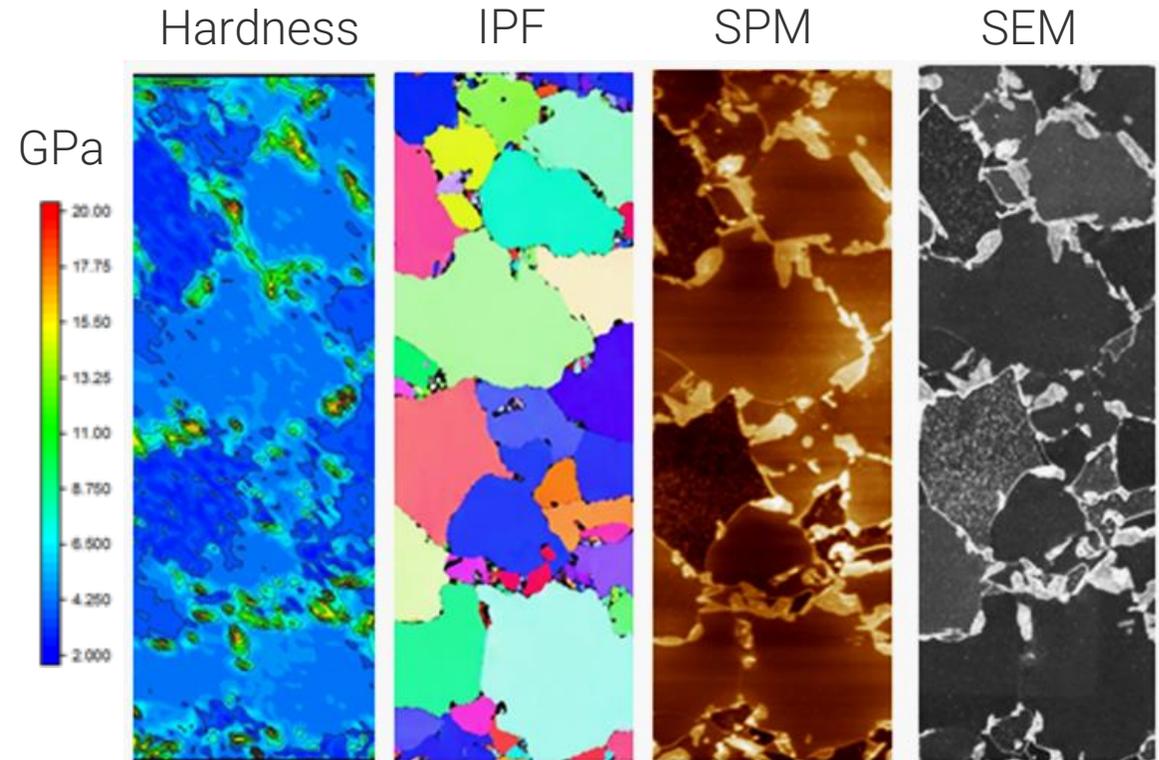
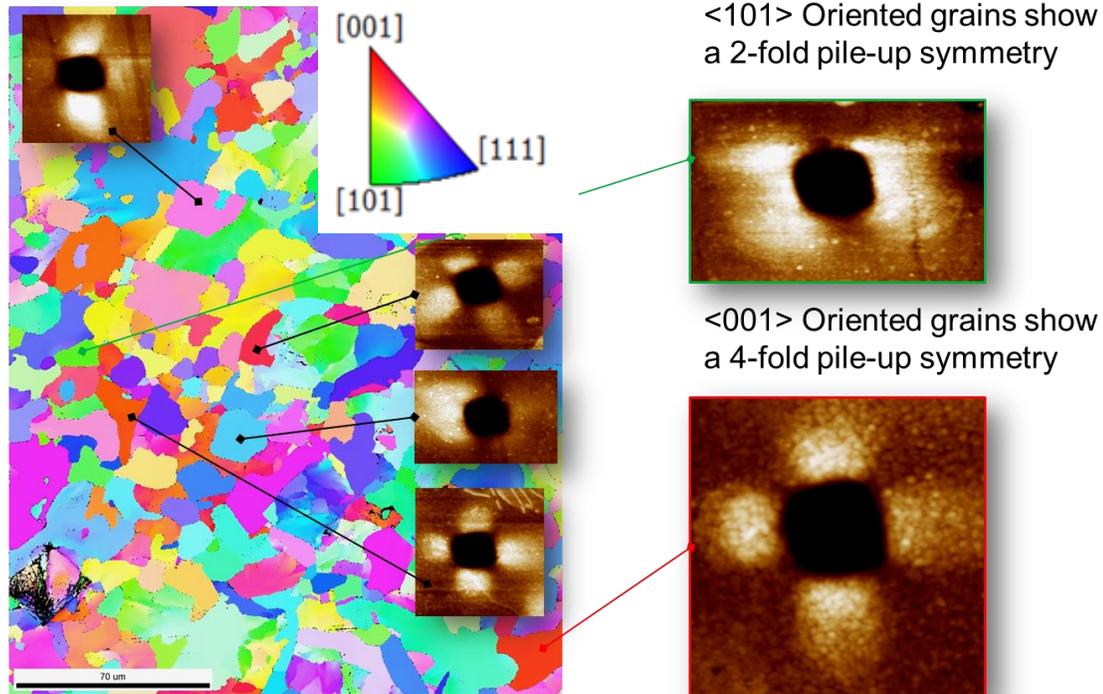
TKD

NanoTribology

High Temperature

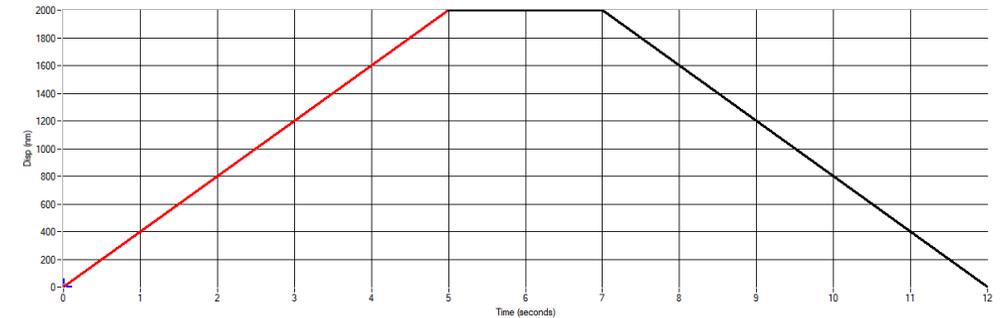
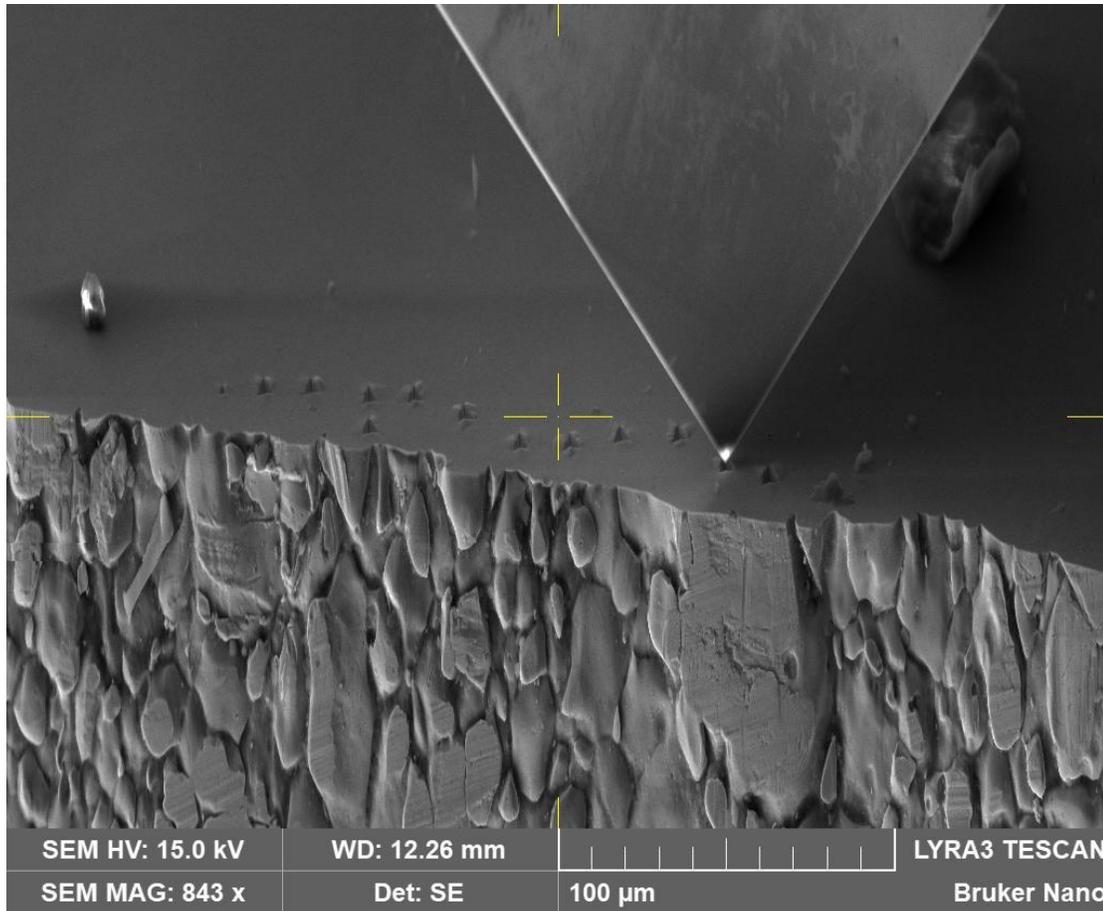
# Correlated XPM and EBSD

Pile-up symmetry depends on crystallographic orientation



Inverse pole figure (IPF) orientation component uses a basic RGB colouring scheme, fit to an inverse pole figure. For cubic phases, full red, green, and blue are assigned to grains whose  $\langle 100 \rangle$ ,  $\langle 110 \rangle$  or  $\langle 111 \rangle$  axes, respectively, are parallel to the projection direction of the IPF.

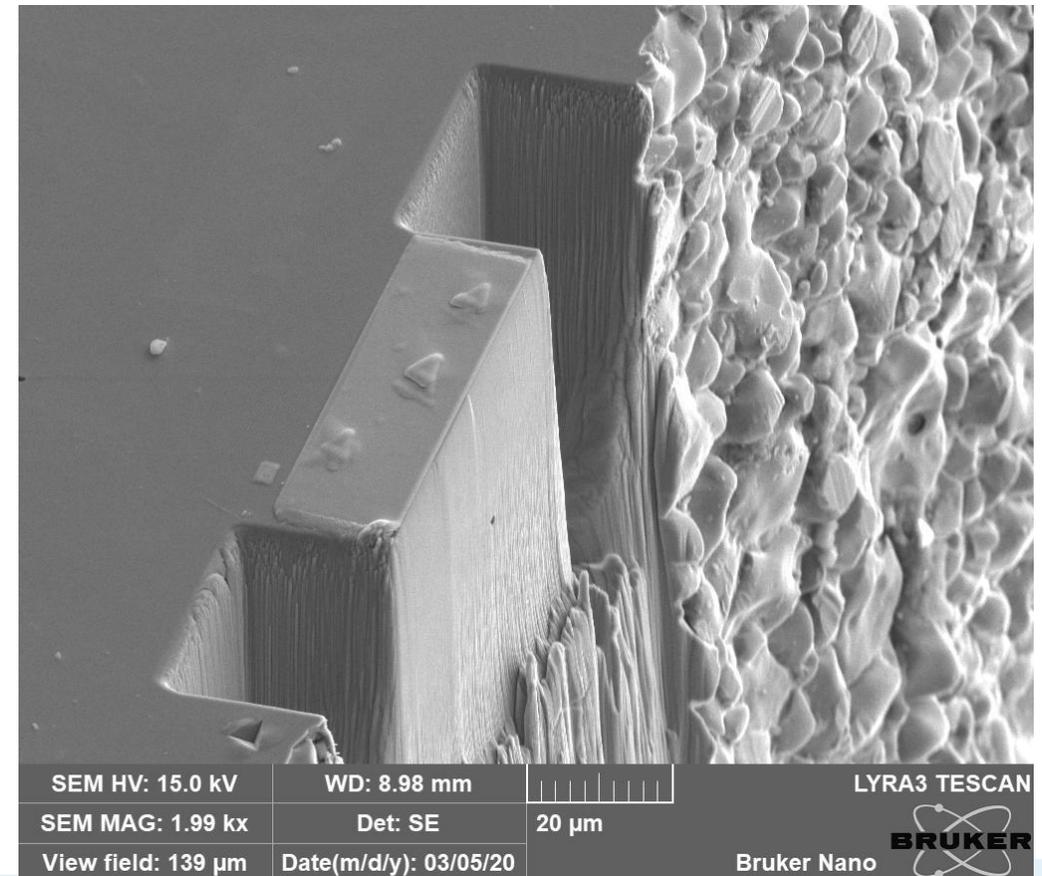
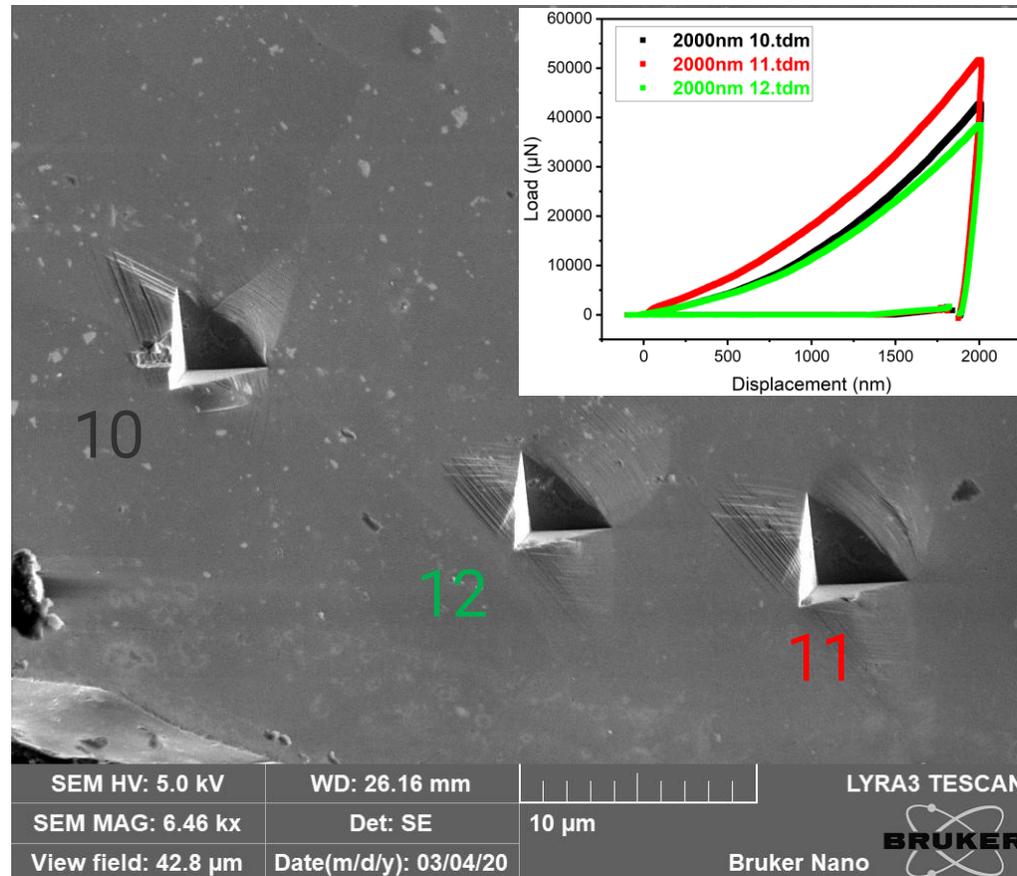
# Indent Positioning and Load Function



- Displacement Control Feedback Loop
- Peak displacement 2μm
- 5-2-5s of Load-Hold-Unload segments
- Cube Corner tip
- Indentation along the edge of sample
- ROI was defined by EBSD map before indentation

# Residual Indents for 3D EBSD

- indents 12&11 made in the same grain.
- indent 11 requires greater applied force to reach the same penetration depth.





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# EBSD technique overview

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## EBSD: What for?

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Understanding the material strength and deformation properties by:

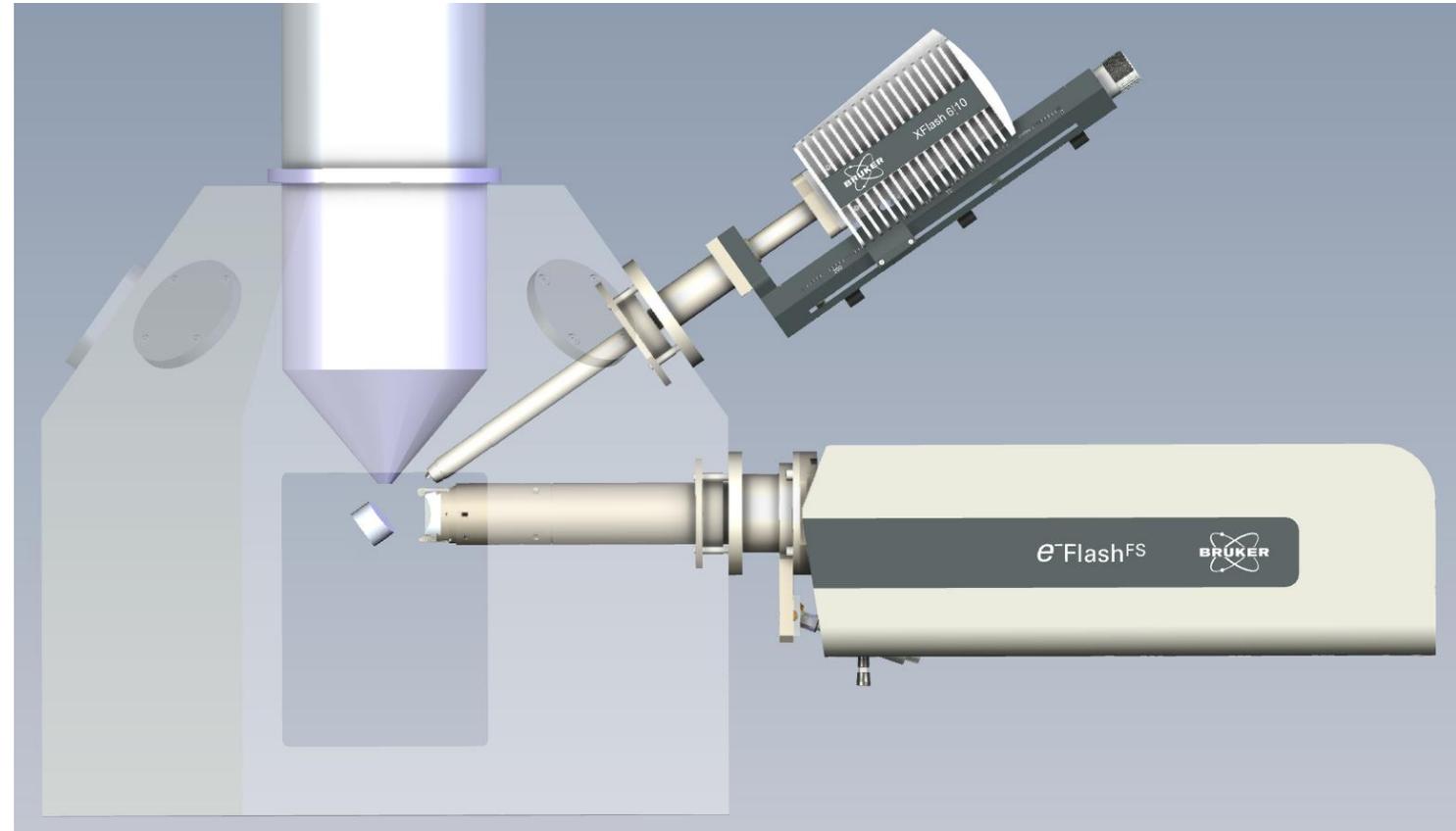
- Measuring crystal orientation
- Analyzing the grain structure
- Distinguishing phases
- For quality control, phase transformation, fracture analysis, strain analysis, tectonophysics studies...



## Hardware - Experimental setup

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- Simultaneous 2D and 3D EDS/EBSD measurement
- Detectors in-situ tilt options to maximize measurement quality
- One software platform



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# ESPRIT QUBE

## 3D EBSD/EDS data processing

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## 3D EBSD overview

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EBSD is an extremely versatile tool:

- microstructure, texture (phase discrimination)
- grain boundaries, dislocations (residual stress)

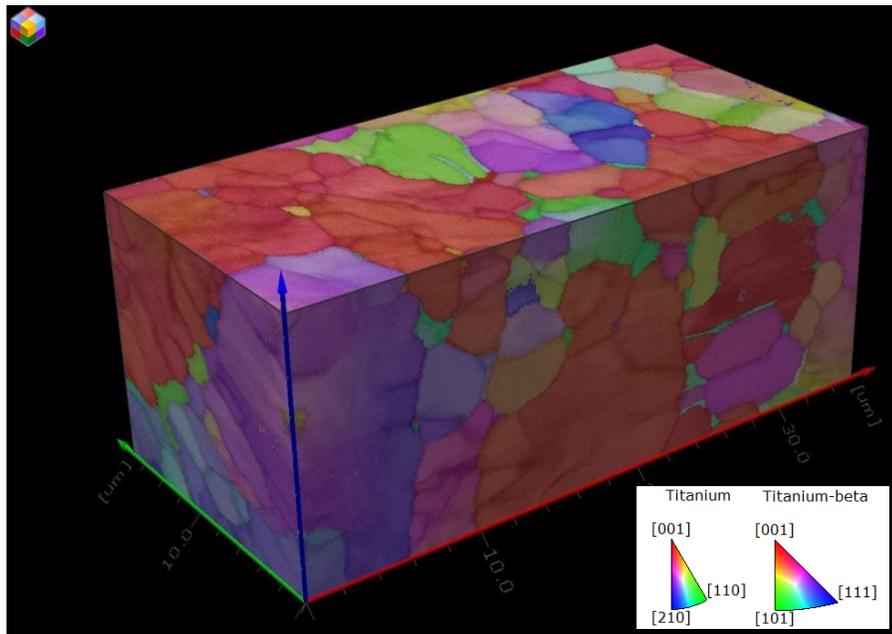
3D EBSD is a specialty tool, brings the most advanced 3D insights into the deformation mechanisms of materials:

- wide range of serial section techniques (destructive)
- slice registration /realignment
- growing list of applications : 5 parameters grain boundary characterization, microstructure characterization in 3D, Nye tensor / Geometrically Necessary Dislocation analysis, ...

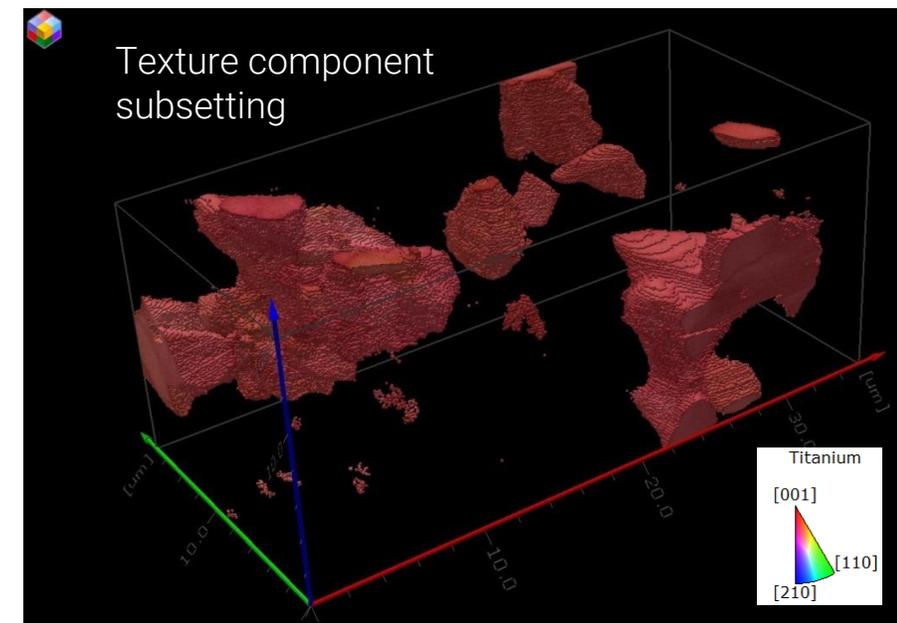
## 3D EBSD data processing with ESPRIT QUBE

### ESPRIT QUBE:

- Advanced postprocessing capabilities for crystal plasticity studies, e.g. GND density distribution
- Multiple advanced slice realignment features
- Multiple subsetting

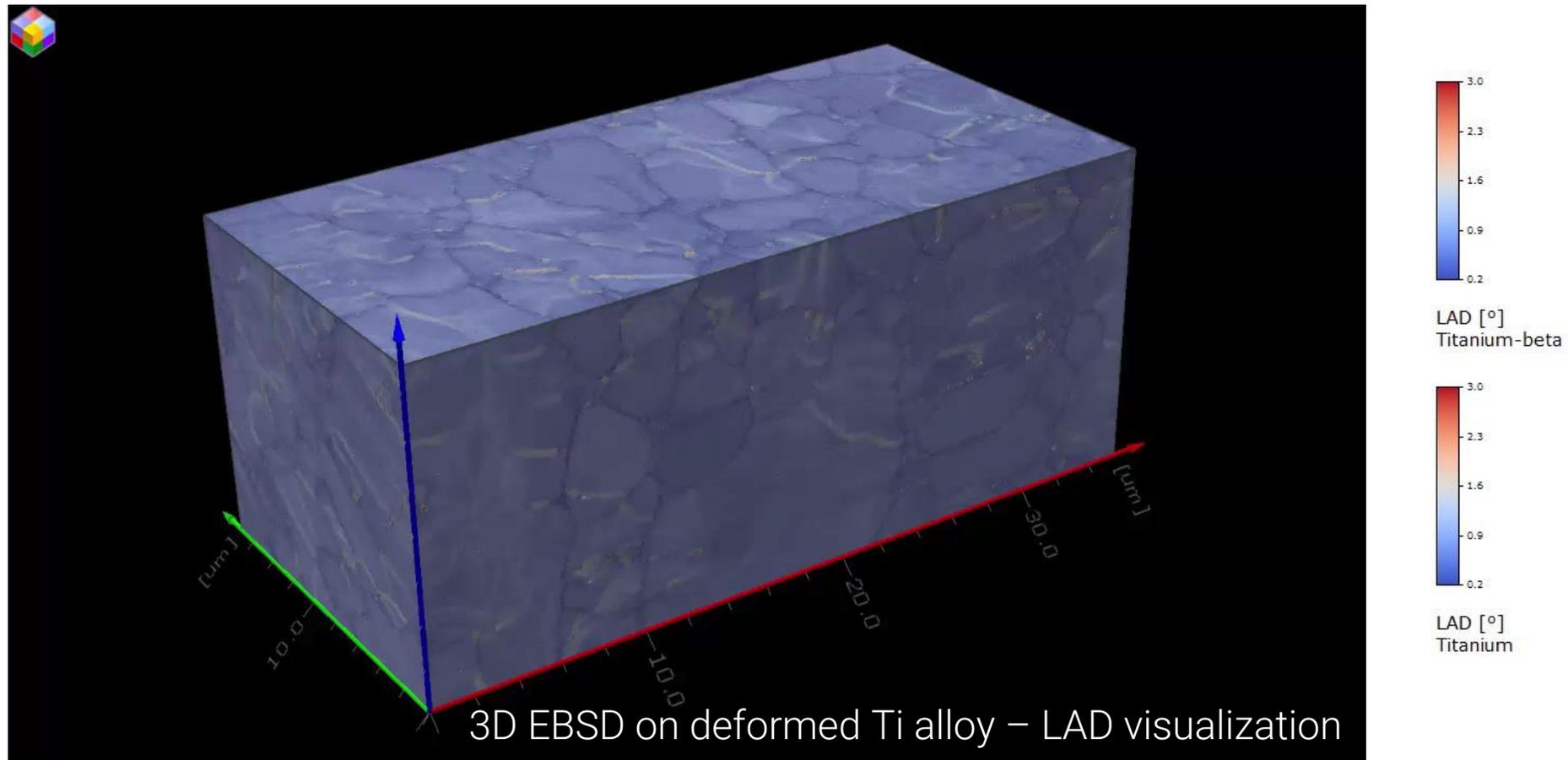


- sample: deformed Ti alloy ( $\alpha$  and  $\beta$  phases)
- Large data cube – 245 slices ( $35 \times 20 \times 20 \mu\text{m}^3$ )
- Serial sectioning using a PFIB-SEM with non-static 3D
- Slice preparation time:  $\sim 2 \text{min/slice}$
- 3D EBSD data acquisition time:  $\sim 7 \text{min/slice}$



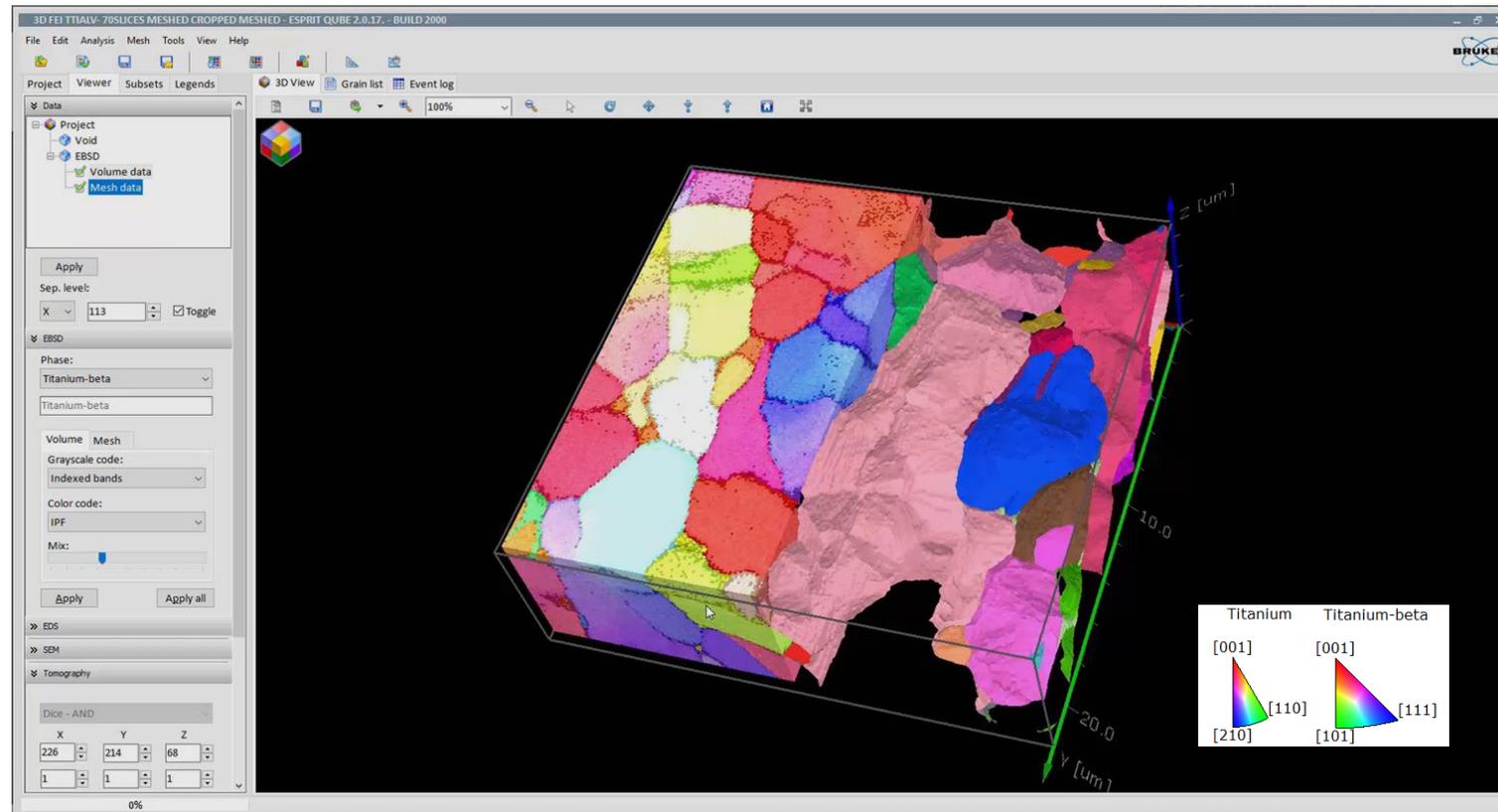
## 3D EBSD data processing with ESPRIT QUBE

- Local Average Disorientation after slice realignment & data filtering



# 3D EBSD data processing with ESPRIT QUBE

- Grain Boundary network (Ti alloy) IPF and grain orientation mean (Euler coloring)

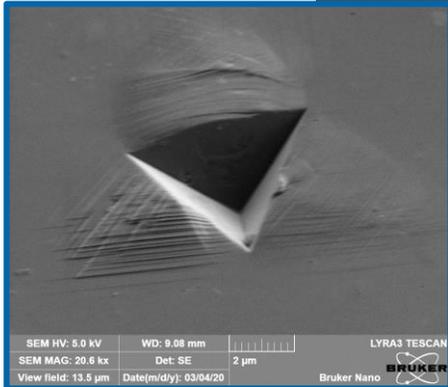


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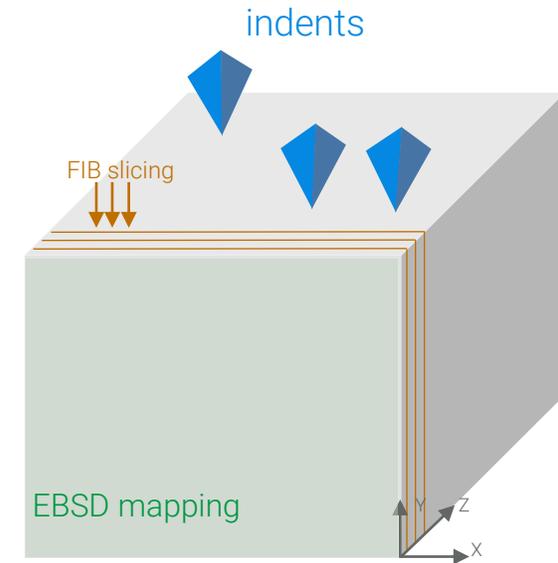
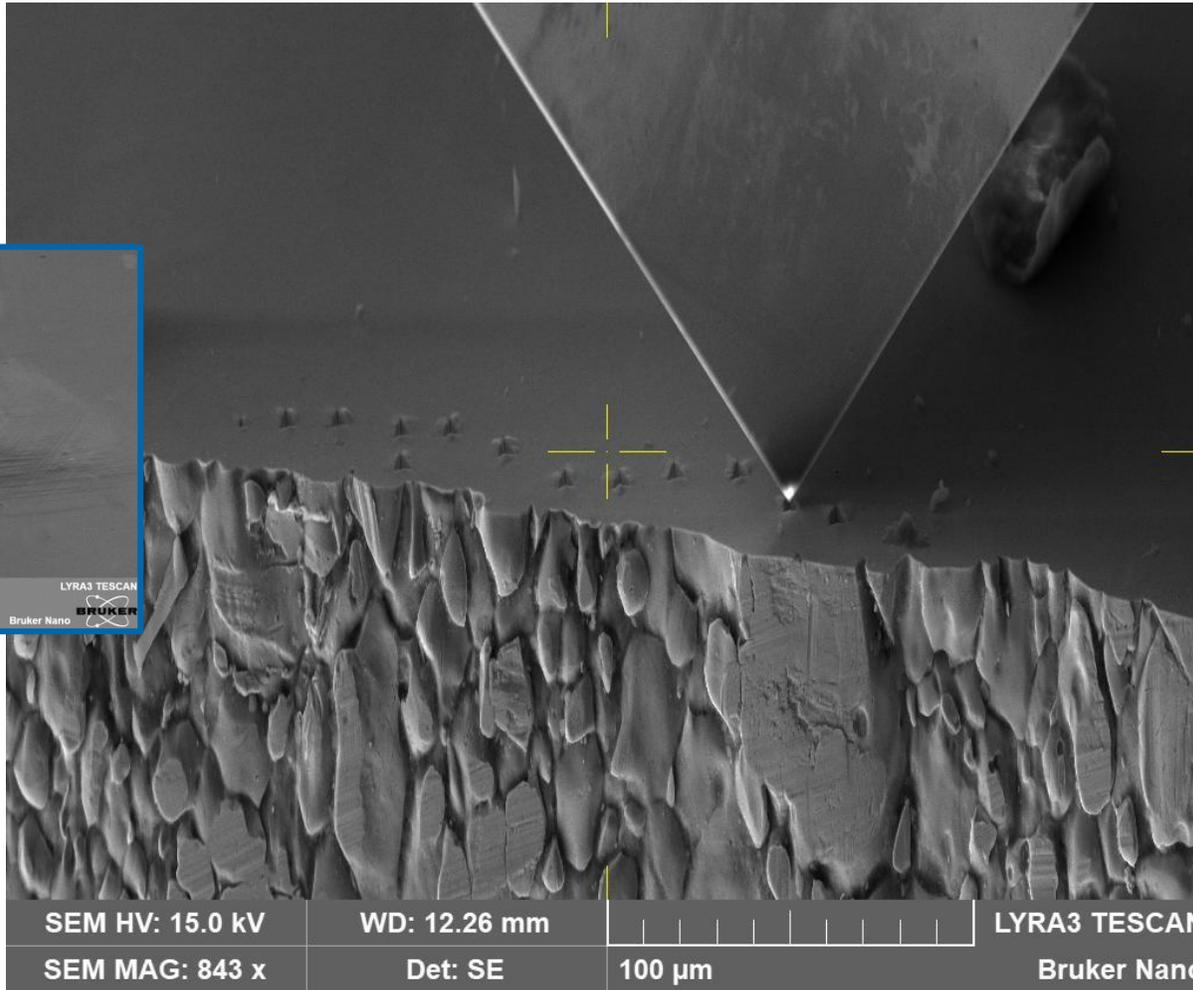
# 3D EBSD measurement and data processing

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# Experimental setup - indentation



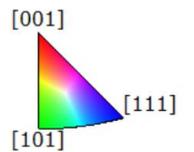
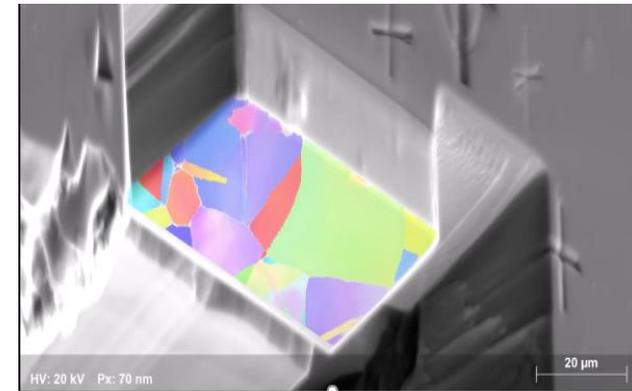
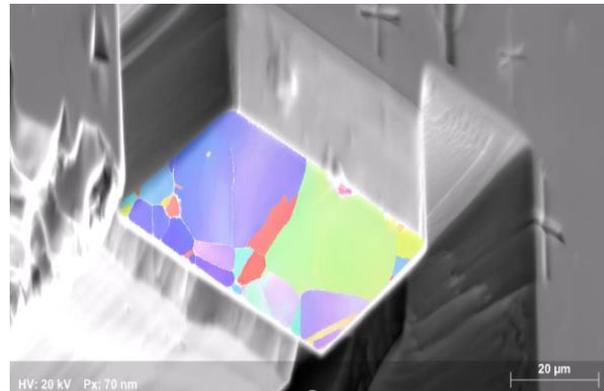
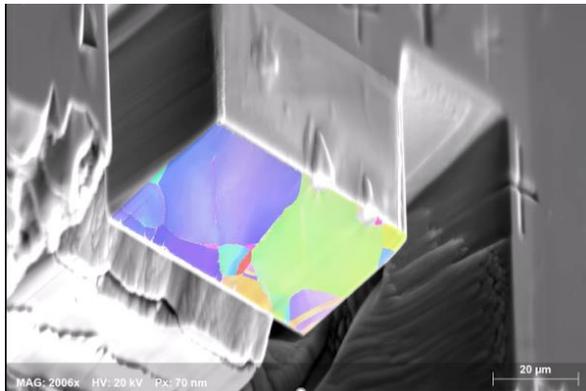
Stacking faults visible at the surface



Voxel size is  $70\text{nm}^3$   
 245 slices,  $56(x) \times 35(y) \times 171(z) \mu\text{m}$   
 160x120 pixels  
 2 ms

## Experimental setup – 3D EBSD measurement

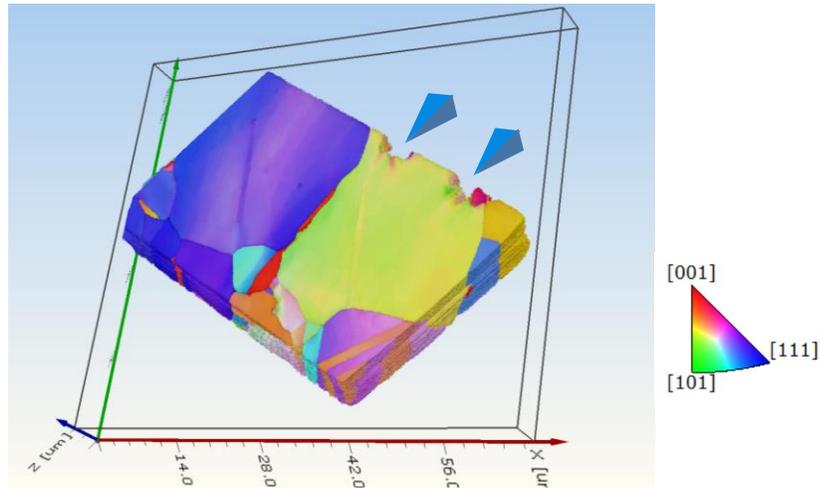
- Watch the recording to access the video of the 3D EBSD measurement



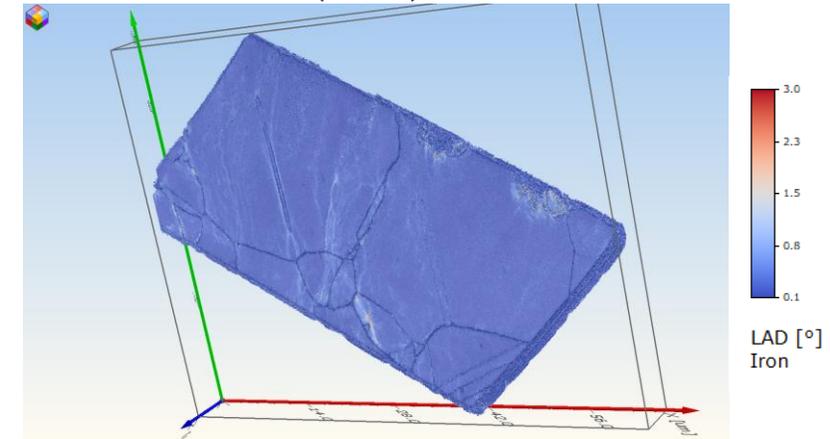
# 3D EBSD data processing

*Rigid slice realignment and noise filtering applied on selected area below (~37 Millions of points)*

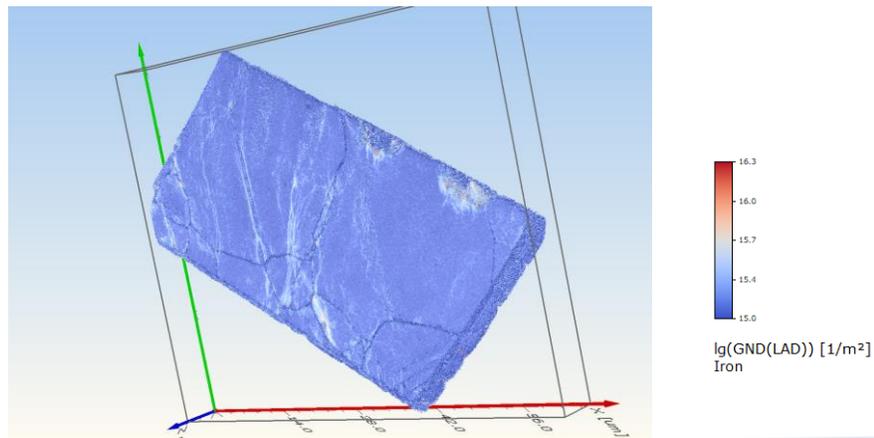
- IPF



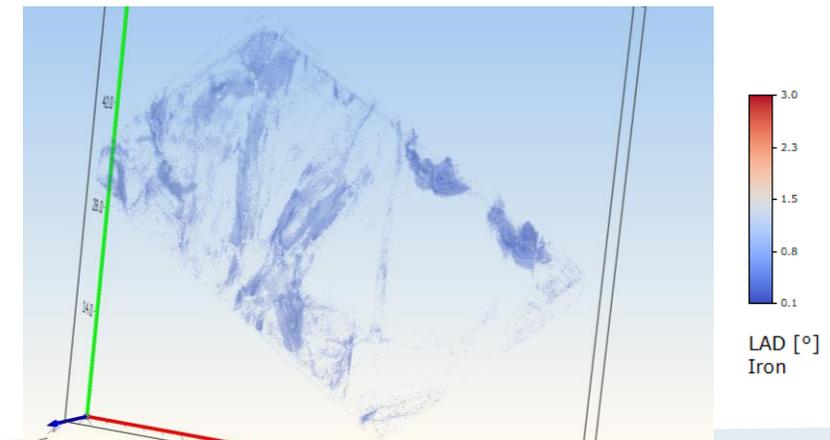
- Local Average Disorientation (LAD)



- GND

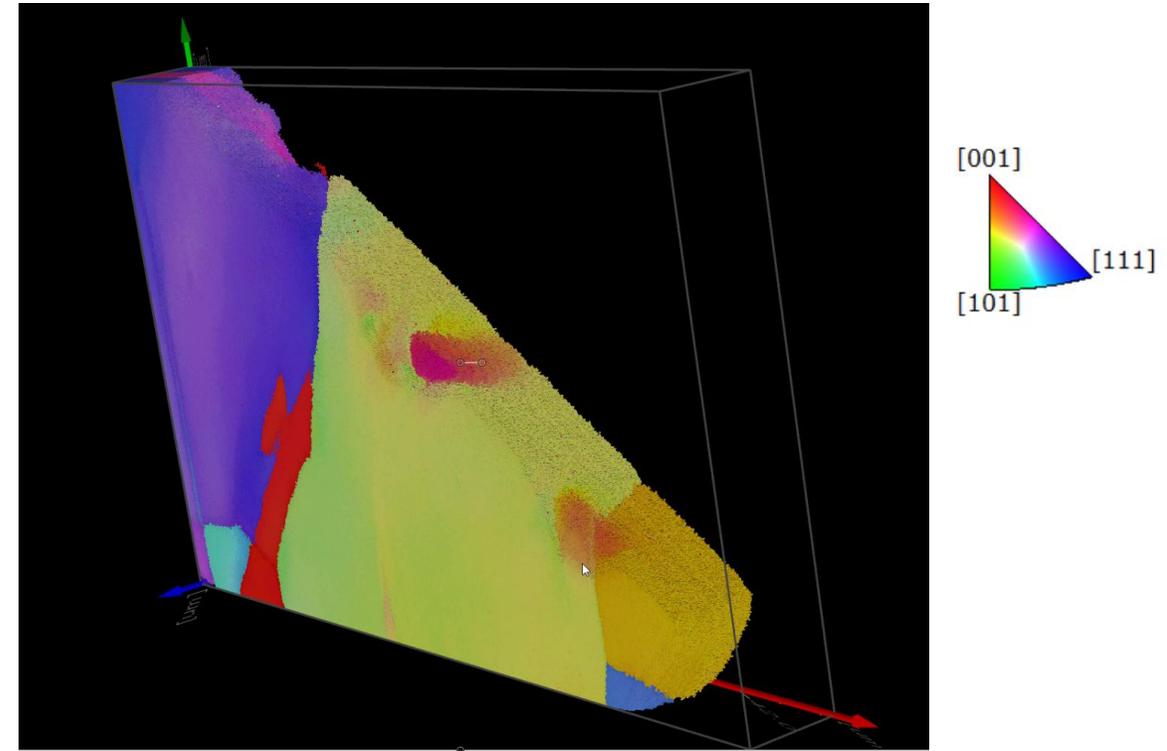
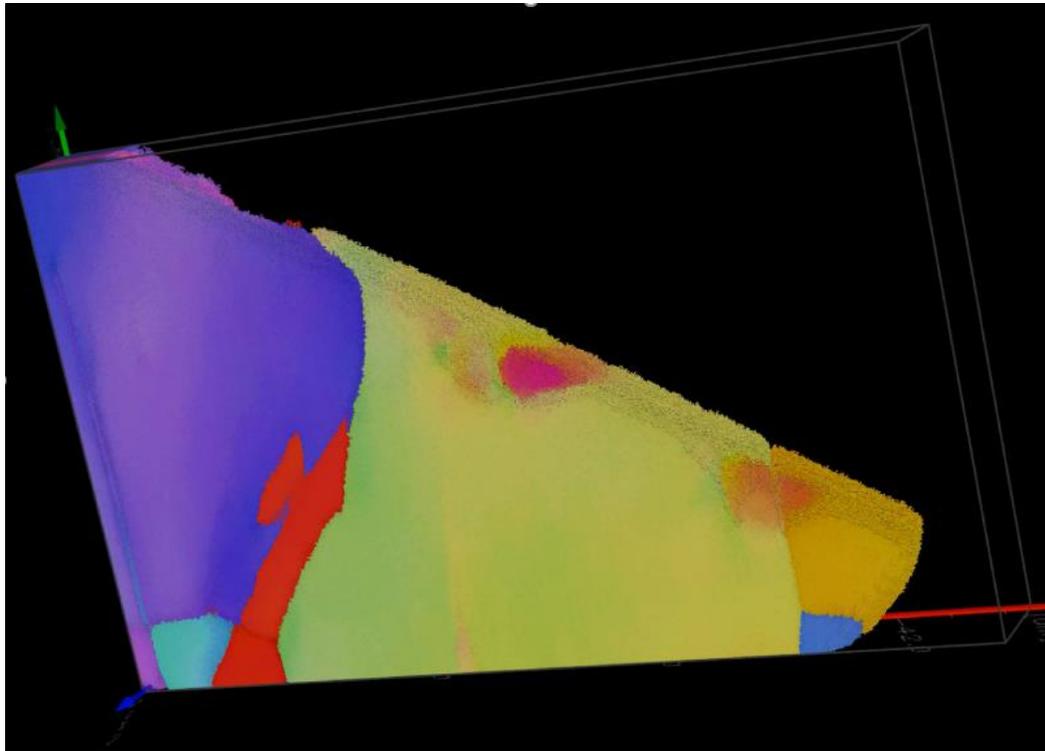


- LAD scalar color scheme



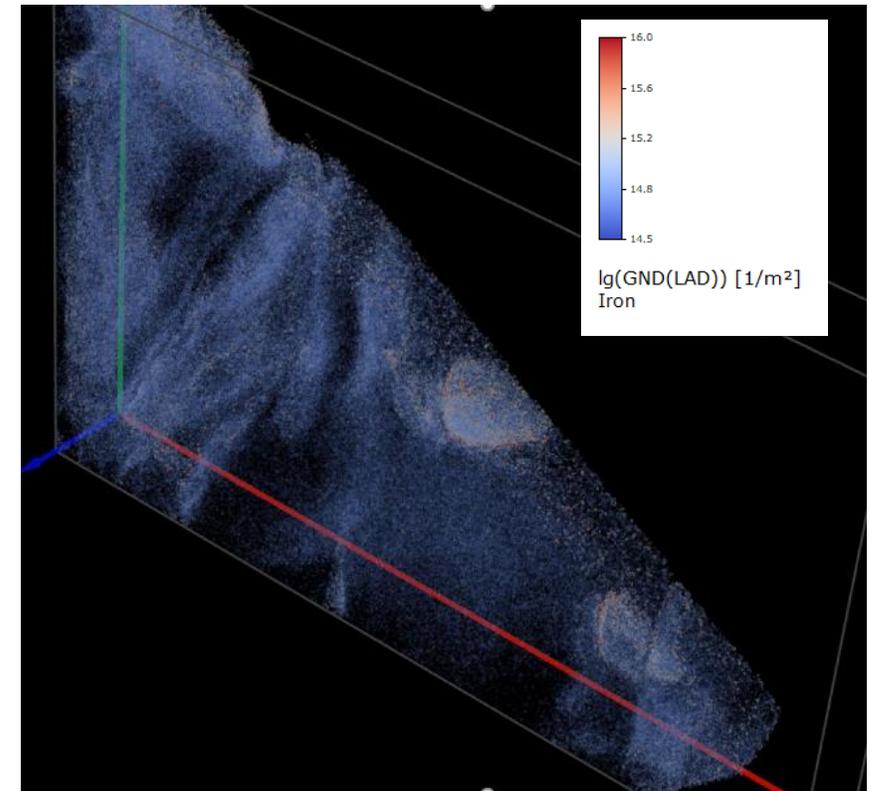
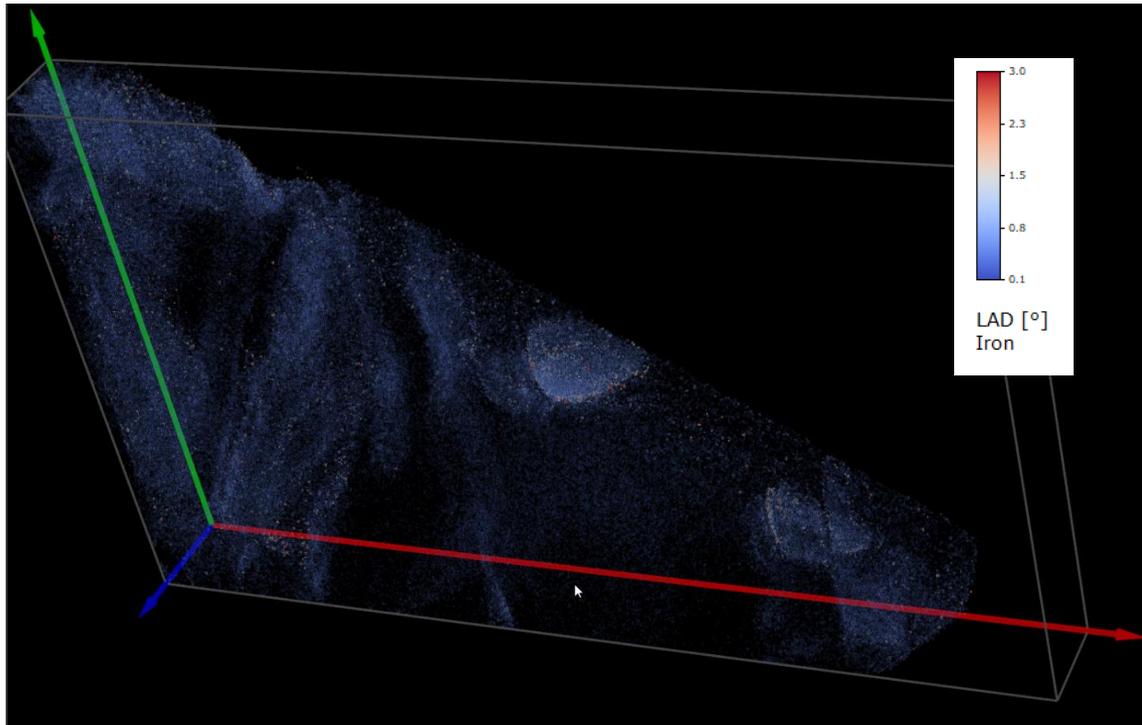
## 3D EBSD – Orientation Distribution (IPF)

- Close-up on the indents area – plastic deformation area clearly visible
- Indent 11 (right) has a smaller plastic deformation zone. It was made in the vicinity of a grain boundary.



# 3D EBSD - Local Average Disorientation (LAD/KAM) and Geometrically Necessary Dislocation (GND)

- LAD : plastic deformation delimited by low angle boundaries
- GND: they are stacking up at low angle boundaries



*Plastic deformation zones clearly delimited by LAD and GND distribution. Indent 11 (right) has a smaller plastic deformation zone and required more applied force because of the vicinity of a grain boundary which reduces the mobility of dislocations.*

## Some suggested references...

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- N. Zaafarani, D. Raabe, R.N. Singh, F. Roters, S. Zaefferer, Three-dimensional investigation of the texture and microstructure below a nanoindent in a Cu single crystal using 3D EBSD and crystal plasticity finite element simulations, *Acta Materialia* 54 (2006) 1863-1876
- M. Rester, C. Motz, R. Pippan, Microstructural investigation of the volume beneath nanoindentations in copper, *Acta Materialia* 55 (2007) 6427–6435
- “Assessment of geometrically necessary dislocation levels derived by 3D EBSD“, P.J. Konijnenberg *et al.*, *Acta Mat.* 99 (2015) 402–414, doi: 10. 1016/j.actamat.2015.06.051
- “ 3D HR-EBSD Characterization of the plastic zone around crack tips in tungsten single crystals at the micron scale “ S. Kalácska *et al.*, *Acta Mat.* 200 (2020) 211-222
- “Investigation of geometrically necessary dislocation structures in compressed cu micropillars by 3-dimensional HR-EBSD“ S. Kalácska *et al.*, *Mat. Sci. Eng. A.* 770 (2020) 138499, doi: 10.1016/j.msea.2019.138499 .

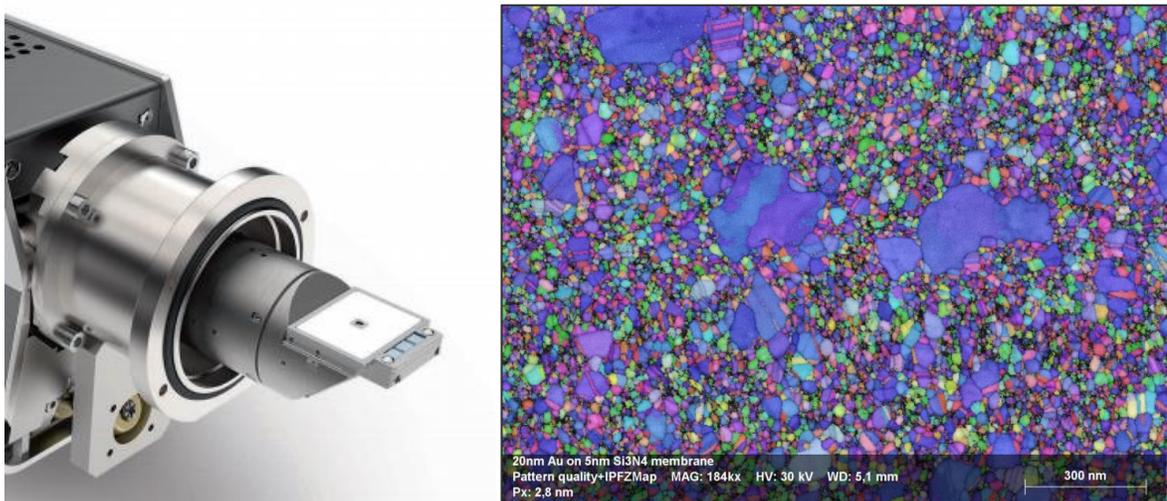
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# Advanced applications: combination with OPTIMUS TKD

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# Tensile testing of nanowires or thin films

OPTIMUS 2 TKD Detector



- OPTIMUS 2 is an add-on option of the e-Flash EBSD detectors
- On-axis Transmission Kikuchi Diffraction
- Effective spatial resolution 1.5 nm
- ARGUS™ imaging system with near real-time visualization

SEM PicoIndenter with OPTIMUS 2 detector



- Tensile testing of thin films
- Strain, grain structure and deformation mapping
- Suitable with Push-to-Pull device

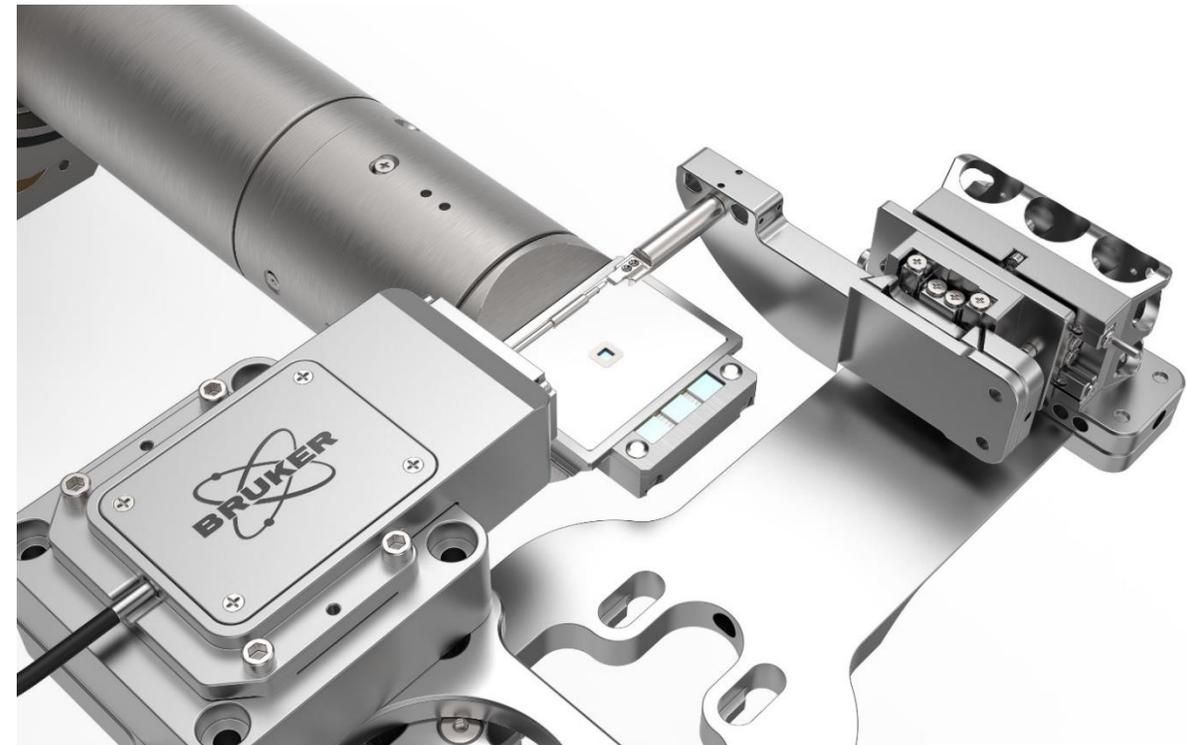
# Integration of multiple instruments

## OPTIMUS 2 and PicoIndenter PI 89 with Push-to-Pull device

Time Resolved Measurements during in-situ experiments:

- *Near real-time visualization* at up to **125,000 pixels/second** during in-situ tensile testing with Push-to-Pull device on PI 89
- Time resolved mapping at up to **600 points/second** during in-situ tensile testing – quantify every microstructural change in the sample
- Same capabilities apply to in-situ heating and electrical biasing experiments

Sample and detectors setup for Time Resolved Measurements during in-situ tensile testing of nanomaterials





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# Summary

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## Summary

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Combined mechanical testing with 3D EBSD measurement allow :

- Correlating mechanical properties with the complete microstructural features (GB, twins, low angle boundary, GNDs...)
- Study of plastic deformation mechanisms, crystal plasticity
- Study the strength of heterogenous materials
- Fracture analysis (cantilever)
- Micropillar compression
- Investigation of residual stress with HR-EBSD, 3D shape of deformation zone, ...
- Understanding the role of crystal orientation and different dislocations in the plastic deformation, ...
  
- Further: Tensile/heating testing on thin lamella



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Q&A

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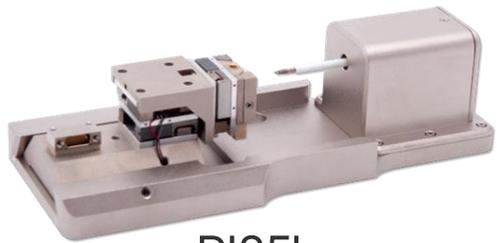


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# Appendix

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# Enabling Your Control Mode



PI85L  
„True Load Control“

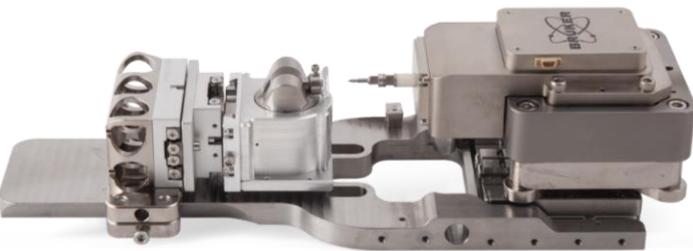
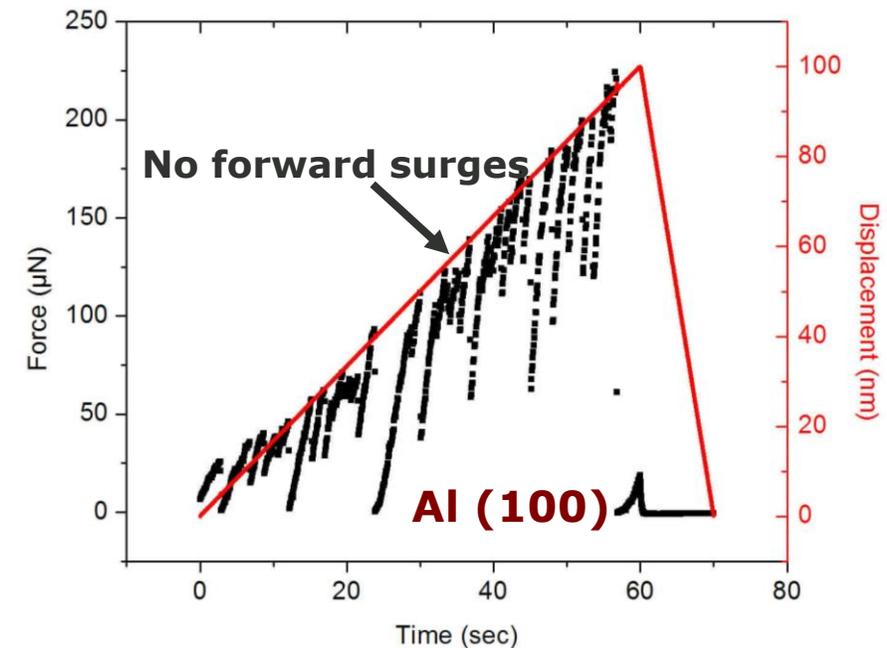


## Performech II



- 1.2MHz Data Sample Rate
- 78kHz Feedback Control Loop
- 38kHz Data Acquisition Rate
- 20nN Force Noise Floor
- 0.1nm Displ. Noise Floor

## Displacement Control



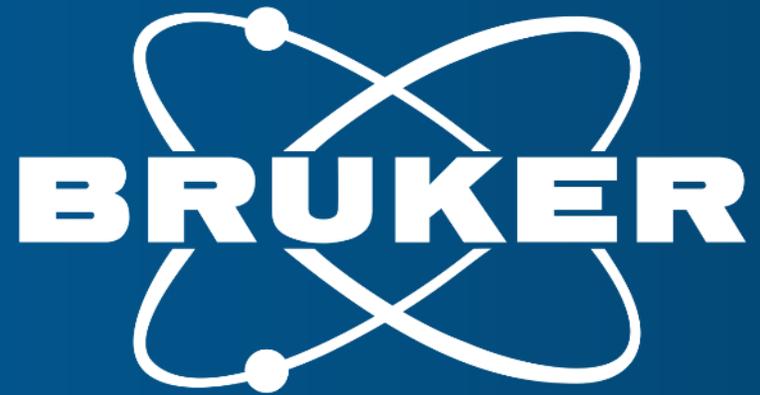
PI89  
„True Load Control“  
„True Displacement Control“



BRUKER NANO ANALYTICS WEBINAR

**Thank you!**

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Innovation with Integrity